Docket No.: O11.2I-13210-US01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Tsuyoshi MATSUDA; Tatsuhiko HIRANO; Junhui

OH; Atsunori KAWAMURA; Kenji SAKAI

Application No.: 10/574115

Filed: September 30, 2004

For: POLISHING COMPOSITION AND POLISHING

METHOD

Examiner: Michael A. Marcheschi

Group Art Unit: 1793 Confirmation No.: 5670

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

RESPONSE TO RESTRICTION REQUIREMENT

This communication is in response to the Restriction Requirement dated **January** 16, 2008.

If an extension of time is required to make this response timely and no separate petition is enclosed, Applicants hereby petition for an extension of time sufficient to make the response timely. In the event that this response requires the payment of government fees and payment is not enclosed, please charge Deposit Account No. 22-0350.